# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Application of: Mamoru Kosakai, Kazunori Ishimura, Teruyasu Fujita

For: PLASTIC FILM ELECTROSTATIC ADSORPTION APPARATUS AND ELECTRONIC STATIC ADSORPTION METHOD

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on July 18, 2001, Signed

Carolyn Thompson

### PRELIMINARY AMENDMENT

Box Patent Application Director of Patents Washington, D.C. 20231

Dear Sir:

Kindly amend the above-identified application as follows:

In the Specification

After "BACKGROUND OF THE INVENTION", please add:

#### --CLAIM OF PRIORITY

This application claims priority of Japanese Patent Application No. 2000-223029, filed July 24, 2000.--

At page 1, please replace the third paragraph with the following:

--It is necessary to fix the plastic films comprised of metal, organic compounds or inorganic compounds and so forth on a sample stand. In cases in which these plastic films are subjected to surface processing and treatment such as heat treatment or plasma treatment, or are adhered or joined with other materials.--

Page 6, please replace the third full paragraph with the following:

- Fig. 1A is a cross-sectional view showing the entire apparatus, and Fig. 1B being an

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enlarged view of the encircled portion of Fig. 1A.-

Page 7, please replace the first and second paragraph with the following:

- The following provides a detailed explanation of the present invention with references

to Figs. 1A, 1B and 2.

Fig. 1A is a cross-sectional view showing the entire apparatus, while Fig. 1B is an enlarged view of the encircled portion of Fig. 1A. Fig. 2 is an overhead view showing

an example of an electrostatic adsorption apparatus of the present invention. -

REMARKS

Amendments have been made to the specification for the purposes of bringing the drawing figures into conformance with the specification, for figure numbers in the specification to conform to the drawing figures, to claim priority of a prior Japanese application, and to improve the readability of the application. The amendments made herein are of a clerical, typographical or grammatical nature. It is submitted that the proposed amendments to the drawings and specification do not constitute new matter or

In view of the foregoing, consideration and an early allowance of this application are earnestly solicited.

Respectfully submitted, Sierra Patent Group, Ltd.

Dated: July 18, 2001

are such to require reexamination.

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The following paragraphs provide the "As Amended" changes in a Marked-up format.

#### IN THE SPECIFICATION

#### Marked-up

The third paragraph on page 1.

It is necessary to fix the plastic films comprised [or] of metal, organic compounds or inorganic compounds and so forth on a sample stand. In cases in which these plastic films are subjected to surface processing and treatment such as heat treatment or plasma treatment, or are adhered or joined with other materials.

The third paragraph on page 6.

[Fig. 1 is a cross-sectional view showing an example of a plastic film electrostatic adsorption apparatus of the present invention, with] Fig. 1A [being] is a cross-sectional view showing the entire apparatus, and Fig. 1B being an enlarged view of the encircled portion of Fig. 1A.

## Marked-up

The first and second paragraphs on page 7.

The following provides a detailed explanation of the present invention with references to Figs. [1] <u>1A</u>, <u>1B</u> and 2.

[Fig. 1 is a cross-sectional view showing an example of a plastic film electrostatic adsorption apparatus of the present invention.] Fig. 1A [being] is a cross-sectional view showing the entire apparatus, while Fig. 1B is an enlarged view of the encircled portion of Fig. 1A. Fig. 2 is an overhead view showing an example of an electrostatic adsorption apparatus of the present invention.